

Day : Saturday  
Date: 5/15/2004

Time: 15:06:30

## PALM INTRANET

## Inventor Name Search Result

Your Search was:

Last Name = OKUMURA  
First Name = TOMOHIRO

*Inventor Name Search*  
*09/511,398*

| Application# | Patent#    | Status       | Date Filed              | Title   | Inventor Name 44                       |
|--------------|------------|--------------|-------------------------|---|--|
| 10720092     | Not Issued | 020<br>28/12 | 11/25/2003<br>438/      | PLASMA PROCESSING METHOD  | OKUMURA, IFW<br>TOMOHIRO               |
| 10675922     | Not Issued | 030<br>28/12 | 09/29/2003<br>438/570   | PLASMA DOPING METHOD AND PLASMA DOPING APPARATUS                      | OKUMURA, IFW<br>TOMOHIRO               |
| 10649670     | Not Issued | 030<br>17/03 | 08/28/2003<br>216/56    | PLASMA PROCESSING METHOD AND APPARATUS                                | OKUMURA, IFW<br>TOMOHIRO               |
| 10647479     | Not Issued | 030<br>17/02 | 08/26/2003<br>427/569   | PLASMA PROCESSING METHOD AND APPARATUS                                | OKUMURA, IFW<br>TOMOHIRO               |
| 10615851     | Not Issued | 030<br>17/03 | 07/10/2003<br>118/1723  | APPARATUS FOR PLASMA DOPING   | OKUMURA, IFW<br>TOMOHIRO               |
| 10611867     | Not Issued | 030<br>17/03 | 07/03/2003<br>118/1728  | METHOD AND APPARATUS FOR PLASMA DOPING                                | OKUMURA, IFW<br>TOMOHIRO               |
| 10408261     | Not Issued | 030<br>17/02 | 04/08/2003<br>427/569   | PLASMA PROCESSING METHOD AND APPARATUS AND TRAY FOR PLASMA PROCESSING | OKUMURA, IFW<br>TOMOHIRO<br>Eric Fells |
| 10365449     | Not Issued | 020<br>28/11 | 02/13/2003<br>315/1673  | PLASMA PROCESSING METHOD AND APPARATUS                                | OKUMURA, IFW<br>TOMOHIRO               |
| 10357456     | Not Issued | 020<br>28/12 | 02/04/2003<br>156/34535 | PLASMA PROCESSING METHOD AND APPARATUS                                | OKUMURA, IFW<br>TOMOHIRO               |
| 10324031     | 6707253    | 150          | 12/20/2002<br>?         | MATCHING CIRCUIT AND PLASMA PROCESSING APPARATUS                      | OKUMURA, TOMOHIRO                      |
| 10207183     | Not Issued | 041<br>17/02 | 07/30/2002<br>427/569   | PLASMA PROCESSING METHOD AND APPARATUS                                | OKUMURA, IFW<br>TOMOHIRO               |
| 10197465     | Not Issued | 041<br>17/05 | 07/18/2002<br>216/45    | DRY ETCHING METHOD AND APPARATUS                                      | OKUMURA, IFW<br>TOMOHIRO               |
| 10179857     | Not Issued | 041<br>17/03 | 06/26/2002<br>156/345   | PLASMA PROCESSING METHOD AND APPARATUS                                | OKUMURA, IFW<br>TOMOHIRO               |
| 10114238     | Not Issued | 041<br>17/05 | 04/03/2002<br>216/186   | PLASMA PROCESSING METHOD AND APPARATUS                                | OKUMURA, IFW<br>TOMOHIRO               |

|  |            |             |                         |   |                       |
|--|------------|-------------|-------------------------|---|-----------------------|
| 10081587                                 | 6630792    | 150         | 02/21/2002              | HIGH FREQUENCY POWER SOURCE, PLASMA PROCESSING APPARATUS, INSPECTION METHOD FOR PLASMA PROCESSING APPARATUS, AND PLASMA PROCESSING METHOD | OKUMURA, TOMOHIRO     |
| 10060350<br>2002007405                   | Not Issued | 041<br>1763 | 02/01/2002<br>154/34548 | METHOD AND APPARATUS FOR PLASMA PROCESSING  | OKUMURA, TOMOHIRO IFW |
| 09968810<br>2002003874                   | Not Issued | 071<br>1763 | 10/03/2001<br>154/345   | PLASMA PROCESSING METHOD AND APPARATUS  | OKUMURA, TOMOHIRO IFW |
| 09918823                                 | Not Issued | 041<br>2821 | 08/01/2001<br>315/169.4 | PLASMA PROCESSING METHOD AND APPARATUS THEREOF  | OKUMURA, TOMOHIRO IFW |
| 09903069                                 | 6517670    | 150         | 07/11/2001<br>?         | ETCHING AND CLEANING APPARATUS  | OKUMURA, TOMOHIRO     |
| 09789799                                 | 6432730    | 150         | 02/22/2001              | PLASMA PROCESSING METHOD AND APPARATUS  | OKUMURA, TOMOHIRO     |
| 09631671                                 | 6346915    | 150         | 08/03/2000              | PLASMA PROCESSING METHOD AND APPARATUS  | OKUMURA, TOMOHIRO     |
| 09589204                                 | Not Issued | 161<br>nd   | 06/08/2000              | METHOD AND APPARATUS FOR PLASMA PROCESSING  | OKUMURA, TOMOHIRO     |
| 09569056                                 | 6355573    | 150         | 05/10/2000              | PLASMA PROCESSING METHOD AND APPARATUS  | OKUMURA, TOMOHIRO     |
| 09511398<br>(no parent or child entries) | Not Issued | 071         | 02/23/2000              | PLASMA PROCESSING METHOD AND APPARATUS  | OKUMURA, TOMOHIRO     |
| 09495293                                 | 6342139    | 150         | 02/01/2000              | SPUTTERING SYSTEM   | OKUMURA, TOMOHIRO     |
| 09339621                                 | 6297165    | 150         | 06/24/1999<br>?         | ETCHING AND CLEANING METHODS  | OKUMURA, TOMOHIRO     |
| 09339620                                 | Not Issued | 083<br>1763 | 06/24/1999<br>154/345   | INDUCTIVELY COUPLED DRY ETCHING APPARATUS   | OKUMURA, TOMOHIRO IFW |
| 09339241                                 | 6291937    | 150         | 06/24/1999<br>?         | HIGH FREQUENCY COUPLER, AND PLASMA PROCESSING APPARATUS AND METHOD  | OKUMURA, TOMOHIRO     |
| 09277729                                 | Not Issued | 161<br>nd   | 03/29/1999              | THIN FILM FORMING METHOD AND APPARATUS  | OKUMURA, TOMOHIRO     |
| 09180974                                 | 6177646    | 150         | 11/17/1998              | METHOD AND DEVICE FOR PLASMA TREATMENT  | OKUMURA, TOMOHIRO     |
| 09048254                                 | 6093457    | 150         | 03/26/1998              | METHOD FOR PLASMA PROCESSING  | OKUMURA, TOMOHIRO     |
| 08996705                                 | 6030667    | 150         | 12/24/1997              | APPARATUS AND METHOD FOR APPLYING RF POWER  | OKUMURA, TOMOHIRO     |

|                     |            |                   |                 |   |                   |
|---------------------|------------|-------------------|-----------------|---|-------------------|
|                     |            |                   |                 | APPARATUS AND METHOD FOR GENERATING PLASMA AND APPARATUS AND METHOD FOR PROCESSING WITH PLASMA  |                   |
| <del>08807853</del> | Not Issued | 161<br><i>okd</i> | 02/26/1997      | APPARATUS AND METHOD FOR APPLYING RF POWER, APPARATUS AND METHOD FOR GENERATING PLASMA, AND APPARATUS AND METHOD FOR PROCESSING WITH PLASMA | OKUMURA, TOMOHIRO |
| 08749847            | 5922223    | 150               | 11/15/1996      | PLASMA PROCESSING METHOD AND APPARATUS  | OKUMURA, TOMOHIRO |
| 08656851            | 5888413    | 150               | 05/30/1996      | PLASMA PROCESSING METHOD AND APPARATUS  | OKUMURA, TOMOHIRO |
| 08651606            | 5711850    | 150               | 05/22/1996      | PLASMA PROCESSING APPARATUS   | OKUMURA, TOMOHIRO |
| 08528164            | 5558722    | 150               | 09/14/1995      | PLASMA PROCESSING APPARATUS   | OKUMURA, TOMOHIRO |
| 08518307            | 5916820    | 150               | 08/23/1995<br>7 | THIN FILM FORMING METHOD AND APPARATUS  | OKUMURA, TOMOHIRO |
| 08447936            | 5693236    | 150               | 05/23/1995      | WATER-REPELLENT SURFACE STRUCTURE AND ITS FABRICATION METHOD  | OKUMURA, TOMOHIRO |
| <del>08447525</del> | Not Issued | 161<br><i>okd</i> | 05/23/1995      | METHOD AND APPARATUS FOR PROCESSING WITH HELICON WAVE PLASMA  | OKUMURA, TOMOHIRO |
| 08389229            | 5609690    | 150               | 02/15/1995      | VACUUM PLASMA PROCESSING APPARATUS AND METHOD   | OKUMURA, TOMOHIRO |
| 08054137            | 5372648    | 150               | 04/30/1993      | PLASMA CVD SYSTEM   | OKUMURA, TOMOHIRO |
| <del>07912817</del> | Not Issued | 161<br><i>okd</i> | 07/13/1992      | PLUG FOR MOLTEN METAL REFINING VESSEL   | OKUMURA, TOMOHIRO |
| 07910626            | 5265850    | 150               | 07/08/1992      | REFRACTORY FOR GAS BLOWING FOR MOLTEN METAL REFINING VESSEL   | OKUMURA, TOMOHIRO |

Inventor Search Completed: No Records to Display.

|                          |           |            |        |
|--------------------------|-----------|------------|--------|
| Search Another: Inventor | Last Name | First Name | Search |
|                          | okumura   | tomohiro   |        |

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**PALM INTRANET**

Time: 15:23:51

## Inventor Name Search Result

Your Search was:

Last Name = HARAGUCHI

First Name = HIDEO

| Application# | Patent#    | Status      | Date Filed         | Title  | Inventor Name 19            |
|--------------|------------|-------------|--------------------|--|-----------------------------|
| 10685459     | Not Issued | 020<br>1703 | 10/16/2003<br>118/ | PLASMA PROCESSING APPARATUS  | HARAGUCHI, HIDEO <i>FFW</i> |
| 09768065     | 6642533    | 150         | 01/24/2001         | SUBSTRATE DETECTING METHOD AND DEVICE  | HARAGUCHI, HIDEO            |
| 09511787     | 6648976    | 150         | 02/23/2000         | APPARATUS AND METHOD FOR PLASMA PROCESSING   | HARAGUCHI, HIDEO            |
| 09511398     | Not Issued | 071         | 02/23/2000         | PLASMA PROCESSING METHOD AND APPARATUS   | HARAGUCHI, HIDEO            |
| 09443145     | 6447613    | 150         | 11/19/1999         | SUBSTRATE DECHUCKING DEVICE AND SUBSTRATE DECHUCKING METHOD  | HARAGUCHI, HIDEO            |
| 09315463     | 6254683    | 150         | 05/20/1999         | SUBSTRATE TEMPERATURE CONTROL METHOD AND DEVICE  | HARAGUCHI, HIDEO            |
| 09291657     | 6276892    | 150         | 03/23/1999         | WAFER HANDLING APPARATUS   | HARAGUCHI, HIDEO            |
| 09291148     | 6340281    | 150         | 04/15/1999         | METHOD AND APPARATUS FOR POSITIONING A DISK-SHAPED OBJECT  | HARAGUCHI, HIDEO            |
| 09266656     | 6255223    | 150         | 03/11/1999         | SUBSTRATE HANDLING METHOD AND APPARATUS, AND ATTRACTIVE FORCE INSPECTION METHOD AND APPARATUS USED THEREWITH | HARAGUCHI, HIDEO            |
| 09180974     | 6177646    | 150         | 11/17/1998         | METHOD AND DEVICE FOR PLASMA TREATMENT   | HARAGUCHI, HIDEO            |
| 08946966     | Not Issued | 161         | 10/08/1997         | VIDEO CAMERA WITH DUAL RECORDING MEDIUMS FOR CONTINUOUS RECORDING  | HARAGUCHI, HIDEO            |
| 08932074     | 5974217    | 150         | 09/17/1997         | AN INFORMATION TRANSMISSION SYSTEM HAVING A REDUCED NUMBER   | HARAGUCHI, HIDEO            |

|                 |                |     |            |   |                     |
|-----------------|----------------|-----|------------|---|---------------------|
|                 |                |     |            | OF STORED PROGRAMS AND<br>RECORDING MEDIA<br>PLAYBACK DRIVES  |                     |
| <u>08814018</u> | <u>5851296</u> | 150 | 03/10/1997 | VACUUM PROCESSING<br>APPARATUS AND METHOD   | HARAGUCHI,<br>HIDEO |
| <u>08774899</u> | <u>5721803</u> | 150 | 12/27/1996 | A VIDEO ON DEMAND SYSTEM<br>WHICH DUBS VIDEO<br>PROGRAMS WHEN THERE IS<br>NO IDLE PLAYBACK MEANS                                      | HARAGUCHI,<br>HIDEO |
| <u>08749847</u> | <u>5922223</u> | 150 | 11/15/1996 | PLASMA PROCESSING<br>METHOD AND APPARATUS   | HARAGUCHI,<br>HIDEO |
| <u>08740192</u> | Not<br>Issued  | 161 | 10/24/1996 | DATA<br>TRANSMITTING/RECEIVING<br>DEVICE, DATA TRANSMISSION<br>DEVICE AND DATA<br>RECORDING/PLAYBACK<br>DEVICE AND METHODS<br>THEREOF | HARAGUCHI,<br>HIDEO |
| <u>08380713</u> | <u>5636963</u> | 150 | 01/30/1995 | METHOD OF HANDLING<br>WAFERS IN A VACUUM<br>PROCESSING APPARATUS  | HARAGUCHI,<br>HIDEO |
| <u>08280353</u> | Not<br>Issued  | 166 | 07/26/1994 | INFORMATION TRANSMISSION<br>SYSTEM  | HARAGUCHI,<br>HIDEO |
| <u>08168230</u> | <u>5450139</u> | 250 | 12/17/1993 | APPARATUS FOR<br>TRANSMITTING VIDEO<br>SIGNALS COMPRISING A<br>MEMORY BACKUP DEVICE   | HARAGUCHI,<br>HIDEO |

Inventor Search Completed: No Records to Display.


|                                 |  |                                    |                                       |
|---------------------------------|--|------------------------------------|---------------------------------------|
|                                 | <b>Last Name</b>                       | <b>First Name</b>                  |                                       |
| <b>Search Another: Inventor</b> | <input type="text" value="haraguchi"/> | <input type="text" value="hideo"/> | <input type="button" value="Search"/> |

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PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = MATSUI

First Name = TAKUYA

| Application#    | Patent#        | Status | Date Filed | Title   | Inventor Name 8 |
|-----------------|----------------|--------|------------|---|-----------------|
| <u>60428600</u> | Not Issued     | 020    | 11/22/2002 | FUSED BICYCLIC NITROGEN-CONTAINING HETEROCYCLES | MATSUI, TAKUYA  |
| <u>10720844</u> | Not Issued     | 019    | 11/21/2003 | FUSED BICYCLIC NITROGEN-CONTAINING HETEROCYCLES | MATSUI, TAKUYA  |
| <u>10179857</u> | Not Issued     | 041    | 06/26/2002 | PLASMA PROCESSING METHOD AND APPARATUS          | MATSUI, TAKUYA  |
| <u>09789799</u> | <u>6432730</u> | 150    | 02/22/2001 | PLASMA PROCESSING METHOD AND APPARATUS          | MATSUI, TAKUYA  |
| <u>09631671</u> | <u>6346915</u> | 150    | 08/03/2000 | PLASMA PROCESSING METHOD AND APPARATUS          | MATSUI, TAKUYA  |
| <u>09569056</u> | <u>6355573</u> | 150    | 05/10/2000 | PLASMA PROCESSING METHOD AND APPARATUS          | MATSUI, TAKUYA  |
| <u>09511787</u> | <u>6648976</u> | 150    | 02/23/2000 | APPARATUS AND METHOD FOR PLASMA PROCESSING      | MATSUI, TAKUYA  |
| <u>09511398</u> | Not Issued     | 071    | 02/23/2000 | PLASMA PROCESSING METHOD AND APPARATUS          | MATSUI, TAKUYA  |

Inventor Search Completed: No Records to Display.

|                                 |                                     |                                     |               |
|---------------------------------|-------------------------------------|-------------------------------------|---------------|
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|                                 | <input type="text" value="matsui"/> | <input type="text" value="takuya"/> |               |

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Day : Saturday  
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Time: 15:31:03

**Inventor Name Search Result**

Your Search was:

Last Name = MITSUHASHI

First Name = AKIO

| Application#    | Patent#    | Status | Date Filed | Title  | Inventor Name 4  |
|-----------------|------------|--------|------------|--|------------------|
| <u>09511398</u> | Not Issued | 071    | 02/23/2000 | PLASMA PROCESSING METHOD AND APPARATUS   | MITSUHASHI, AKIO |
| <u>09339620</u> | Not Issued | 083    | 06/24/1999 | INDUCTIVELY COUPLED DRY ETCHING APPARATUS  | MITSUHASHI, AKIO |
| <u>07771516</u> | 5127306    | 150    | 10/02/1991 | APPARATUS FOR APPLYING PANNING EFFECTS TO MUSICAL TONE SIGNALS AND FOR PERIODICALLY MOVING A LOCATION OF SOUND IMAGE | MITSUHASHI, AKIO |
| <u>07464964</u> | Not Issued | 166    | 01/16/1990 | APPARATUS FOR APPLYING PANNING EFFECTS TO MUSICAL TONE SIGNALS AND FOR PERIODICALLY MOVING A LOCATION OF SOUND IMAGE | MITSUHASHI, AKIO |

**Inventor Search Completed: No Records to Display.**

**Search Another: Inventor**

|   |                                   |
|---|-----------------------------------|
| <b>Last Name</b>                        | <b>First Name</b>                 |
| <input type="text" value="mitsuhashi"/> | <input type="text" value="akio"/> |
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inventor  
Name  
Search*

|   | L # | Hits      | Search Text  | DBs   | Time Stamp          |
|---|-----|-----------|--|---|---------------------|
| 1 | L1  | 40        | (("6707253") or<br>("6630792") or<br>("6517670") or<br>("6432730") or<br>("6346915") or<br>("6355573") or<br>("6297165") or<br>("6291937") or<br>("6177646") or<br>("6093457") or<br>("6030667") or<br>("5922223") or<br>("5888413") or<br>("5711850") or<br>("5558722") or<br>("5916820") or<br>("5609690") or<br>("5372648") or<br>("6648976") or<br>("5851296")) .PN. | USPAT;<br>US-PGPUB<br>; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | 2004/05/15<br>16:42 |
| 2 | L2  | 1236<br>3 | ((427/488-491,534<br>-539,569-597) or<br>(216/66,71,69) or<br>(118/723I,723AN))<br>.CCLS.  | USPAT;<br>US-PGPUB<br>; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | 2004/05/15<br>16:44 |
| 3 | L3  | 0         | ("2and(antennacoi<br>l)") .PN.   | USPAT;<br>US-PGPUB<br>; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | 2004/05/15<br>16:45 |
| 4 | L4  | 2485      | 2 and (antenna<br>coil)  | USPAT;<br>US-PGPUB<br>; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | 2004/05/15<br>16:47 |
| 5 | L5  | 117       | plasma adj trap  | USPAT;<br>US-PGPUB<br>; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | 2004/05/15<br>16:46 |
| 6 | L6  | 6         | 4 and 5  | USPAT;<br>US-PGPUB<br>; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | 2004/05/15<br>16:48 |

*EAST Search -*



|   | L # | Hits | Search Text                   | DBs   | Time Stamp          |
|---|-----|------|-------------------------------|---|---------------------|
| 7 | L7  | 44   | 5 and (antenna<br>coil) not 6 | USPAT;<br>US-PGPUB<br>; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | 2004/05/15<br>16:47 |
| 8 | L8  | 191  | 4 and trap not 6              | USPAT;<br>US-PGPUB<br>; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | 2004/05/15<br>16:48 |